

BOOK

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1. C. S. Roper, V. Radmilovic, R. T. Howe, and R. Maboudian, "Characterization of polycrystalline 3C-SiC films deposited from precursors of 1,3-disilabutane and dichlorosilane," *Journal of Applied Physics*, **103**, 084907 (2008).
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